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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICATION SERIAL NO. Filed Concurrently Herewith
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INVENTORSHIP Weimin Li et al.
ASSIGNEE Micron Technology, Inc.
GROUP ART UNIT Unknown
EXAMINER Unknown
ATTORNEY'S DOCKET NO. MI22-1208
TITLE: Low k Interlevel Dielectric Layer Fabrication Methods

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. Copies of documents listed on the Form PTO-1449 are enclosed, except that copies of the listed pending applications are not enclosed.

No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 8/30/99

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Dated: 8/30/99

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